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Sheet 1 of 1	GROUP ART UNIT: Unassigned	EXAMINER: Unassigned

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Examiner's Initials	Cite No.	U.S. Patent Document Number	U.S. Patent Document Kind Code	Name of Patentee or Applicant of Cited Document	Date of Publication or of issue of Cited Document MM-DD-YYYY
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OTHER ART – NON PATENT LITERATURE DOCUMENTS

Examiner's Initials	Cite No	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue number(s), publisher, city and/or country where published.	Translation (Y/N)	
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